

PATENT ASSIGNMENT COVER SHEET

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Stylesheet Version v1.2

EPAS ID: PAT4294483

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT
CONVEYING PARTY DATA	
Name	Execution Date
SEUNG YUN YANG	02/13/2017
SEUNGHYUN LEE	02/13/2017
RECEIVING PARTY DATA	
Name:	PUSAN NATIONAL UNIVERSITY INDUSTRY UNIVERSITY COOPERATION FOUNDATION OF PUSAN
Street Address:	2(JANGJEON DONG, PUSAN NATIONAL UNIVERSITY), BUSANDAEHAK-RO 63BEON-GIL GEUMJEONG-GU
City:	BUSAN
State/Country:	KOREA, REPUBLIC OF
Postal Code:	46241
PROPERTY NUMBERS Total: 1	
Property Type	Number
Application Number:	15507198
CORRESPONDENCE DATA	
Fax Number:	(512)536-4598
<i>Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.</i>	
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Email:	aoipdocket@nortonrosefulbright.com
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Address Line 1:	98 SAN JACINTO BOULEVARD
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Address Line 4:	AUSTIN, TEXAS 78701-4255
ATTORNEY DOCKET NUMBER:	NCIP.P0035US/11702219
NAME OF SUBMITTER:	MICHAEL R. KRAWZSENEK
SIGNATURE:	/Michael R. Krawzsenek/
DATE SIGNED:	02/28/2017
This document serves as an Oath/Declaration (37 CFR 1.63).	
Total Attachments: 4	
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source=NCIPP0035US_Combined_Decl_Assignment#page4.tif

**COMBINED DECLARATION AND ASSIGNMENT UNDER 37 CFR 1.63(e)
DECLARATION**

As a below-named inventor, I hereby declare that this declaration is directed to the application attached hereto, or to United States Application Number or PCT International Application Number

PCT/KR2015/009033 filed on Aug 28, 2015 (if applicable), entitled:

**ETCHING MASK, MANUFACTURING METHOD THEREFOR, POROUS MEMBRANE
MANUFACTURING METHOD USING ETCHING MASK, POROUS MEMBRANE, FINE
DUST-BLOCKING MASK INCLUDING POROUS MEMBRANE, AND MANUFACTURING
METHOD FOR SURFACE ENHANCED RAMAN SCATTERING ACTIVE SUBSTRATE**

The above-identified application was made or authorized to be made by me.

I believe I am the original inventor or an original joint inventor of a claimed invention in the above-identified application.

I hereby acknowledge that any willful false statement made in this declaration is punishable under 18 USC 1001 by fine or imprisonment of not more than five (5) years, or both.

I have reviewed and understand the contents of the above-identified application, including the claims.

I am aware of the duty to disclose to the United States Patent and Trademark Office all information known to me to be material to patentability as defined in 37 CFR 1.56, including for continuation-in-part applications, material information that became available between the filing date of the prior application and the national or PCT international filing date of the continuation-in-part application.

ASSIGNMENT

For valuable consideration, I, as a below-named assignor, hereby assign to:

**PUSAN NATIONAL UNIVERSITY INDUSTRY UNIVERSITY COOPERATION FOUNDATION OF PUSAN
SAN 30, JANGJEON-DONG, GEUMJEONG-GU, BUSAN, REPUBLIC OF KOREA, 609-735**

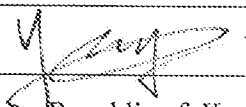
and its successors and assigns (collectively hereinafter called "the Assignee"), the entire right, title, and interest throughout the world in the inventions and improvements that are the subject of the application identified in the above declaration, which is United States Application Number or PCT International Application Number PCT/KR2015/009033 filed on Aug 28, 2015

I authorize and request the attorneys appointed in the above-identified application to hereafter complete this Assignment by inserting above the application number and the filing date of the above-identified application when known, and to correct any typographical errors that may be discovered in this Assignment.

This Assignment includes the above-identified application, any and all United States and foreign patents, utility models, and design registrations granted for any of the inventions and improvements that are the subject of the above-identified application, and the right to claim priority based on the filing date of the

above-identified application under the International Convention for the Protection of Industrial Property, the Patent Cooperation Treaty, the European Patent Convention, and all other treaties of like purposes; and I authorize the Assignee to apply in all countries in my name or in its own name for patents, utility models, design registrations, like rights of exclusion, and inventors' certificates for any of the inventions and improvements that are the subject of the above-identified application; and I agree for myself and my heirs, legal representatives, and assigns without further compensation to perform such lawful acts and to sign such further applications, Assignments, preliminary statements, and other lawful documents as the Assignee may reasonably request to effectuate fully this Assignment.

In witness whereof, I, as a below-named inventor and assignor, intending to be legally bound, have hereunto affixed my signature on the date indicated below next to my signature.

Inventor's Legal Name	YANG, Seung Yun		
Inventor's Signature		Date	Feb. 13, 2017
Residence (City, Country)	Daegu, Republic of Korea		
Mailing Address	20, Dasa-ro 101-gil Dasa-eup Dalseong-gun Daegu 42907, Korea		

Inventor's Legal Name	LEE, Seunghyun		
Inventor's Signature		Date	
Residence (City, Country)	Busan, Republic of Korea		
Mailing Address	101 Dong 203 Ho(Jangnim-dong, SAMGYEONG Apt.)141, Dadae-ro 277beon-gil Saha-gu Busan 49510, Korea		

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ASSIGNMENT

For valuable consideration, I, as a below-named assignor, hereby assign to:

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SAN 30, JANGJEON-DONG, GEUMJEONG-GU, BUSAN, REPUBLIC OF KOREA, 609-735**

and its successors and assigns (collectively hereinafter called "the Assignee"), the entire right, title, and interest throughout the world in the inventions and improvements that are the subject of the application identified in the above declaration, which is United States Application Number or PCT International Application Number PCT/KR2015/009033 filed on Aug 28, 2015

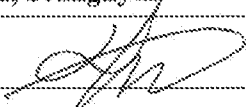
I authorize and request the attorneys appointed in the above-identified application to hereafter complete this Assignment by inserting above the application number and the filing date of the above-identified application when known, and to correct any typographical errors that may be discovered in this Assignment.

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above-identified application under the International Convention for the Protection of Industrial Property, the Patent Cooperation Treaty, the European Patent Convention, and all other treaties of like purposes; and I authorize the Assignee to apply in all countries in my name or in its own name for patents, utility models, design registrations, like rights of exclusion, and inventors' certificates for any of the inventions and improvements that are the subject of the above-identified application; and I agree for myself and my heirs, legal representatives, and assigns without further compensation to perform such lawful acts and to sign such further applications, Assignments, preliminary statements, and other lawful documents as the Assignee may reasonably request to effectuate fully this Assignment.

In witness whereof, I, as a below-named inventor and assignor, intending to be legally bound, have hereunto affixed my signature on the date indicated below next to my signature.

Inventor's Legal Name	YANG, Seung Yun		
Inventor's Signature		Date	
Residence (City, Country)	Daegu, Republic of Korea		
Mailing Address	20, Dasa-ro 101-gil Dasa-eup Dalseong-gun Daegu 42907, Korea		

Inventor's Legal Name	LEE, Seunghyun		
Inventor's Signature		Date	Feb. 13, 2017
Residence (City, Country)	Busan, Republic of Korea		
Mailing Address	101 Dong 203 Ho(Jangnim-dong, SAMGYEONG Apt.)141, Dadae-ro 277beon-gil Saha-gu Busan 49510, Korea		